

TITLE

A-C:H ISFET DEVICE, MANUFACTURING METHOD, AND TESTING

METHODS AND APPARATUS THEREOF

BACKGROUND OF THE INVENTION

5 **Field of the Invention**

The present invention relates to an ISFET, and in particular to a hydrogenated amorphous carbon (a-C:H) ISFET device, manufacturing method, and method and apparatus to measure hysteresis width and drift rate therewith.

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Description of the Related Art

ISFETs (Ion Sensitive Field Effect Transistor) are constructed by substituting a detecting film for the metal gate on the gate oxide of a conventional MOSFET (Metal-Oxide-Semiconductor Field Effect Transistor). When the ISFET is dipped into a solution, the interfacial potential between the detecting film and the solution influences the semiconductor surface since only an extremely thin dielectric (that is, the gate oxide) separates the detecting film from the semiconductor surface. This influences the charge density in the inversion layer of the semiconductor surface, and thereby modulates the channel current through the ISFET. Thus, by utilizing this characteristic, the pH or other ion concentration in a solution can be obtained from the measurement of source/drain current and the gate voltage of the ISFET. The potential difference on the interface between the detecting film and the solution is related to

the ion activity in a solution. The hydrogen ion activity in the solution can be measured using different channel currents caused by different interfacial potential differences in various solutions with different hydrogen ion activity.

5 Patents related to the formation of the ISFET or measurement thereof are listed hereinafter.

U.S. Patent No. 5,350,701 discloses a method of measuring the content of alkaline-group metals, especially the content of calcium ions, utilizing chemosynthesis phosphide group as the detecting film on a gate of an ISFET.

10 U.S. Patent No. 5,387,328 discloses a bio-sensor using ion sensitive field effect transistor with platinum, wherein an enzyme membrane is immobilized on the ion-detecting film to determine the concentration of glucose.

15 U.S. Patent No. 5,414,284 discloses a method of fabricating an ISFET and an ESD protective circuit on the same silicon substrate, wherein a capacitor is utilized as an interface between the protective circuit and a sample solution to the DC leakage current.

20 U.S. Patent No. 5,309,085 integrates the measurement circuit of a creature sensor having ISFET on a wafer. The measured circuit has two ISFET devices, an enzyme ISFET and a reference electrode FET, whose output signal can be amplified by a differential amplifier.

25 U.S. Patent No. 5,061,976 discloses a carbon thin film on the gate oxide of the ISFET and then a 2,6 xylenol electrolytic polymerization film formed thereon.

The ISFET has the ability to detect hydrogen ions and the advantages of small floating time, high reliability, and insensitivity to light. When other film types are covered on the ISFET, other kinds of ions can be detected.

U.S. Patent No. 5,833,824 discloses an ISFET sensor for detecting ion activity in a solution, which includes a substrate and an ISFET semiconductor die. The substrate has a front surface exposed to the solution, a back surface opposite to the front surface and an aperture extending therebetween. A detecting film of the ISFET is mounted on the back surface such that the gate region is exposed to the solution through the aperture.

U.S. Patent No. 4,691,167 discloses a method of measuring ion activation in a solution by combining the ISFET, the reference electrode, the temperature sensor, amplifier circuit and a calculation and memory circuit. Since the sensitivity is a function of the temperature and drain current of ISFET and is decided by a variable of gate voltage, the sensitivity can be obtained by calculating formulas stored in memory.

U.S. Patent No. 5,130,265 discloses a method of fabricating the ISFET with multiple functions. The method uses siloxanic prepolymer as the sensitive film, mixing the solution, photochemistry treatment and heat treatment.

U.S. Patent No. 4,660,063 discloses a method of performing both laser drilling and solid diffusion to form a 3D diode array on the semiconductor wafer. The laser first drills the wafer, and the impurities are then

diffused from the hole to form a cylindrical PN junction and complete a non-planar ISFET structure.

U.S. Patent No. 4,812,220 discloses an ISFET made by fixing the enzyme on the detecting film to measure the concentration of amino acids in food. The enzyme sensor is miniaturized, and can accurately measure even small concentrations.

There are many materials acting as detection membranes of ISFETs, such as, Al_2O_3 , Si_3N_4 , Ta_2O_5 , $\alpha\text{-WO}_3$, $\alpha\text{-Si:H}$ and the like. These thin films are deposited by either sputtering or plasma enhanced chemical vapor deposition (PECVD), therefore, the cost of the thin film fabrication is higher. For commercial purposes, it is important to develop a thin film, with low cost and easy fabrication.

In the ISFET applications, however, many factors such as hysteresis, temperature, and drift behavior affect the accuracy of the measuring results. Since pH-ISFET is a semiconductor device, it is easily influenced by variations in temperature. The variation of the temperature leads to a deviation of the measurement. With reference to the hysteresis behavior, it is related to the change in the pH of the solution (such as $\text{pH}_x \rightarrow \text{pH}_y \rightarrow \text{pH}_z \rightarrow \text{pH}_x$) and the corresponding change in the output voltage of the ISFET (such as $V_{ox1} \rightarrow V_{oy} \rightarrow V_{ox2} \rightarrow V_{oz} \rightarrow V_{ox3}$). At the same pH, the difference between the first output voltage and the final output voltage (such as $V_{ox3}-V_{ox1}$) is defined as the hysteresis width. For drift behavior, the drift rate is defined as the change in the gate voltage per unit time under conditions

in which the source-drain current is stable and the temperature is constant after the intrinsic response of the pH-ISFET is completed. Hence, there is a need to measure the three effects to prevent error.

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SUMMARY OF THE INVENTION

In view of this, an object of the present invention is to provide an a-C:H gate ISFET. The present invention forms the a-C:H layer as the detection membrane of the ISFET by plasma enhanced low pressure chemical vapor deposition (PE-LPCVD).

Another object of the present invention is to provide a method of measuring temperature parameters of an ISFET. In the present invention, the sensitivities of the ISFET at different temperatures are obtained by the source-drain current and gate voltage of the ISFET in a solution, such that temperature parameters (temperature coefficient of the sensitivity) of the ISFET are obtained.

In the method of measuring the temperature parameters of an ISFET according to the present invention, the detecting film is immersed in a buffer solution, and, then, at a predetermined temperature, the pH of the buffer solution is changed to measure and record the source-drain current and the gate voltage of the ISFET to obtain a curve. The temperature parameters at the predetermined temperature are obtained by selecting a fixed current from the curve. The temperature parameters at other temperatures are obtained

by changing the temperature of the buffer solution and the steps of measuring, recording and selecting.

Another object of the present invention is to provide a method of measuring the hysteresis width and drift rate of the a-C:H ISFET to use the reverse compensation method to obtain an accurate output value.

In the method of measuring the hysteresis width of an a-C:H ISFET according to the present invention, first, the drain-source current and then the drain-source voltage are fixed by a constant voltage/current circuit, and the a-C:H ISFET is immersed in a buffer solution. The gate-source output voltage of the a-C:H ISFET is recorded by a voltage-time recorder, and the pH of the buffer solution is changed. The steps of immersing and recording are then repeated to obtain the gate-source output voltages of the ISFET immersed in the buffer solution with different pH. The hysteresis width is the voltage deviation between starting pH and ending pH.

In the method of measuring the drift rate of an a-C:H ISFET according to the present invention, first, the drain-source current and then the drain-source voltage are fixed by a constant voltage/current circuit, and the a-C:H ISFET is immersed in a buffer solution. The gate/source output voltage of the a-C:H ISFET during a constant period is recorded by a voltage recorder. The pH of the buffer solution is changed and the steps of immersing and recording are repeated to obtain the gate-source output voltages of the ISFET immersed in the buffer solution with different pH. The drift rate is the

slope of the gate-source output voltage with respect to time.

Another object of the present invention is to provide an apparatus to measure the hysteresis width and the drift rate. The apparatus of measuring the hysteresis width and the drift rate has an a-C:H ISFET, a buffer solution to contact the ISFET, a light-isolation container to load the buffer and to isolate light, a heater to heat the buffer solution, a constant current/voltage measuring device coupled to the source and drain of the a-C:H ISFET, and a voltage-time recorder to record the output voltage of ISFET.

A detailed description is given in the following embodiments with reference to the accompanying drawings.

15 **BRIEF DESCRIPTION OF THE DRAWINGS**

The present invention can be more fully understood by reading the subsequent detailed description and examples with references made to the accompanying drawings, wherein:

20 Figs. 1a to 1c are cross-sections of the processes of the present invention;

Fig. 2 is a cross-section of an ISFET with gate consisting of a-C:H;

25 Fig. 3 is a schematic structural diagram of the apparatus to measure the temperature parameter of the a-C:H ISFET according to the present invention;

Fig. 4 is a schematic cross-section of the a-C:H ISFET according to the present invention;

Fig. 5 shows a curve related to the source/drain current and the gate voltage of the a-C:H ISFET at 25°C according to the present invention;

5 Fig. 6 shows a curve related to the gate voltage of the a-C:H ISFET and the pH;

Fig. 7 shows a curve related to the sensitivities of the a-C:H ISFET and the temperature according to the present invention;

10 Fig. 8 shows a schematic structure diagram of the apparatus to measure the hysteresis width and drift rate of the a-C:H ISFET according to the present invention;

Fig. 9 shows a schematic diagram of the constant voltage current circuit according to the present invention;

15 Fig. 10 shows the relationship between the hysteresis width and time in pH=6→2→6→10→6 order; and

Fig. 11 shows the relationship between the drift rate of the a-C:H ISFET and the pH.

DETAILED DESCRIPTION OF THE INVENTION

20 The a-C:H gate ion sensitive field effect transistor (a-C:H gate ISFET) according to the present invention is illustrated in Figs. 1a to 1c.

25 As shown in Fig. 1a, a P-type (100) semiconductor substrate 100 with a resistivity ranging from 8 to 12 Ω·m is provided. A pad oxide layer 102 consisting of silicon dioxide with a thickness of 5000Å is formed on the substrate 100 by wet oxidation. A first photoresist pattern (not shown) is formed on the pad oxide layer 102 by conventional photolithography. A dummy gate 103 is

formed to define the subsequent gate area, using the photoresist pattern as a mask to a portion of the pad oxide layer 102.

5 Impurities are then implanted into the semiconductor substrate 100 to form a source/drain 104 beside the dummy gate 103, using the dummy gate 103 as a mask. For example, the impurities implanted herein are boron ions with a dose of 10^{15} cm^{-2} .

10 As shown in Fig. 1b, the dummy gate 103 is removed, namely, the pad oxide layer 102 and the first photoresist pattern are removed by wet etching. An insulating layer 106 consisting of silicon dioxide with a thickness of about 1000\AA is then formed on the semiconductor substrate 100. A second photoresist pattern (not shown) is formed 15 on the insulating layer 106 by photolithography. Next, the insulating layer 106 outside the gate area is removed by the second photoresist pattern as a mask. The residual insulating layer within the gate area is used as a gate oxide layer. Subsequently, the second photoresist 20 layer is removed.

A a-C:H layer 108 is then formed on the insulating layer 106 by plasma enhanced low pressure chemical vapor deposition (PE-LPCVD). The step of forming the a-C:H layer 108 on the gate oxide layer 106 by plasma enhanced 25 low pressure chemical vapor deposition (PE-LPCVD) is illustrated as follows. First, the semiconductor substrate 100 with the gate oxide layer 106 is disposed into a PE-LPCVD system. During this process, the base pressure of the PE-LPCVD system is adjusted at least 10^{-6} torr. Next, the temperature of the semiconductor

substrate 100 is maintained between 140°C~160°C (preferably 150°C). A mixing gas consisting of methane and hydrogen is then fed into PE-LPCVD system, wherein, in the mixing solution, the ratio of methane and hydrogen is about 30 to 70. Further, the flow ratio of the mixing gas is controlled between 6 to 10 standard cubic centimeter per minute (SCCM), preferably 8 SCCM. The process pressure of the PE-LPCVD is maintained between 0.08 to 0.1 torr, preferably 0.09 torr. Finally, the RF power supply is then turned on, and the RF power thereof is set between 145W to 160W, preferably 150W, for a time interval. After that, the a-C:H gate layer 108 is obtained on the oxide layer 106 for the a-C:H ISFET.

For example, the a-C:H layer 108 with a thickness of least 1000Å is formed on the insulating layer 106. A two-layer gate consisting of the gate oxide layer 106 and the a-C:H layer 108 is fabricated. Thus, an a-C:H ISFET is obtained. The a-C:H ISFET has a channel length of about 50µm and a channel width of about 1000µm. Thus, the aspect ratio (channel width/channel length) of the present a-C:H ISFET is 20.

Next, as shown in Fig. 1c, an interconnecting process is performed to obtain the ion sensitive field effect transistor (ISFET) using conventional interconnect steps for MOS. Thus, an insulating layer 100 is formed on the source/drain 104, and a metal wire 112 is formed on the insulating 110 by etching and sputtering. Finally, a sealing layer 114 consisting of the insulator is formed to seal the metal wire excluding the a-C:H

layer 108. For example, the metal wire 112 can be aluminum, and the sealing layer 114 can be epoxy resin.

The use of plasma enhanced low pressure chemical vapor deposition to form the a-C:H detection membrane provides a simple process and easily formed a-C:H detection membrane on a large area surface of the substrate.

Fig. 2 is a cross-section of the a-C:H ISFET according to the present invention. The structure of this ISFET is similar to that of MOSFET. The difference between the ISFET and MOSFET is that the metal gate of the MOSFET is replaced by an a-C:H detection membrane 35, an aqueous solution 36 and reference electrode 38. The circuits are formed by contacting the metal wire 31, preferably consisting of Al, with the source/drain 33. Since the a-C:H detection membrane 35 contacts the detected solution 36, the whole device in addition to the a-C:H detection membrane 35 must be enclosed by a sealing layer 37 consisting of a material with good insulating property, such as epoxide resin. The reference electrode 38 provides a detecting base.

The a-C:H detection membrane 35 of the ISFET is immersed in the solution 36 during operation, such that the point of transformation from chemical equivalence into electrical equivalence within the ISFET occurs with contact between the a-C:H detection membrane 35 and the aqueous solution 36. The reaction mechanism of the ionic activity within the solution is the interface potential obtained from the interface between the aqueous solution 36 and the a-C:H detection membrane 35 immersed in the

aqueous solution 36. The interface potential varies with the ionic activities of various aqueous solutions. In addition, the interface potential regulates the channel conduction of the ISFET and results in the change of current within the source/drain 33.

Fig. 3 shows a systematic structure diagram according to the present invention. An ISFET using a-C:H as a detection membrane (called a-C:H ISFET) is immersed in a buffer solution 2 such as the phosphate buffer solution that is stored in a container (not titled). The source/drain (not shown) of the a-C:H ISFET 1 connects a test fixer 3 through two connecting wires 331 and 321, respectively, to convey the electrical signals obtained by measuring the source/drain to a current/voltage measuring device 4, such as the Keithley-236 current/voltage measuring device for data processing.

Also, a reference electrode 5 is disposed in the buffer solution 2, with one end connected to the test fixer 3 through the connecting wire 331. A plurality of heaters 6 is disposed outside the container and connected to a PID temperature controller 7. A thermometer 8 connected to the PID temperature controller 7 detects the temperature of the buffer solution 2. The above-mentioned elements such as the buffer solution 2, the elements contacting the buffer solution 2 and the heater 6 are placed in a light-isolating container 9 to protect the measured data from the effect of light.

It should be noted that the interfacial potential between the a-C:H membrane and the solution and the characteristic difference of charge density in the

reverse layer of the semiconductor surface are used to measure needed data (such as the source-drain current or the gate voltage) and thus obtain the temperature parameters of the ISFET.

5 Fig. 4 is a schematic cross-section of the a-C:H ISFET according to the present invention. The a-C:H ISFET is formed on a semiconductor substrate 20 such as a p-type silicon substrate. A pair of source/drain regions 21 separated from each other is formed approaching the 10 top surface of the semiconductor substrate 20 and each region 21 is connected to the test fixer 3 outside through an aluminum contact plug 22 and an aluminum wire 23. On the semiconductor substrate 20 between the two drain/source regions 21, a gate oxide 24, such as a 15 silicon oxide layer, and an a-C:H detection membrane 25 are formed sequentially. An epoxy resin 26 seals the device but exposes the a-C:H detection membrane 25. As well, a metal-aluminum layer 27 is formed at the bottom of the semiconductor substrate 20 to shield light and 20 decrease its influence on charge carriers.

With reference to apparatus shown in Fig. 3 and Fig. 4, the temperature parameters of the a-C:H ISFET of the present invention can be obtained according to a method as follows. First, with regard to the measurement of the 25 sensitivity, the detection membrane of the a-C:H ISFET contacts with the buffer solution. The temperature of the buffer solution is fixed, such as at 25°C, and the pH of the buffer solution is changed at the same time. The curve related to the source-drain current and the gate 30 voltage of the a-C:H ISFET is measured and recorded by

the Keithley-236 current/voltage measuring device. Fig. 5 shows curves related to the statistical results, and both the source-drain current and the gate voltage of the a-C:H ISFET rise as the pH of the buffer resolution increases.

Next, a fixed current of the curve (like $80\mu A$) is selected to obtain a curve related to the gate voltage and the pH at a specific temperature (like $25^\circ C$) as shown in Fig. 6, wherein the sensitivity of the a-C:H ISFET at $25^\circ C$ is 57.36 mV/pH . It is found that the gate voltage of the a-C:H ISFET is in direct proportion to the pH of the buffer solution and the slope of the curve is the sensitivity of the a-C:H ISFET at the specific temperature.

Moreover, in order to measure the sensitivity of the a-C:H ISFET at different temperatures, only the temperature of the buffer solution needs to be changed, such as between $5^\circ C$ ~ $55^\circ C$, with the above step repeated at each temperature. Table 1 shows the sensitivity of the ISFET at the different temperatures.

Table 1 the sensitivity of the ISFET at the different temperatures

Temperature ($^\circ C$)	Sensitivity (mV/pH)
5	53.68
15	55.43
25	56.92
35	59.23
45	61.5
55	62.8

A curve showing the obtained sensitivities at different temperatures is shown in Fig. 7, wherein the sensitivity is in direct proportion to the rising temperature and the slope of the curve is about 5 0.2032mV/pH°C. Namely, the temperature parameter of the a-C:H ISFET is about 0.2032mV/pH°C.

Fig.8 shows a schematic diagram to measure the hysteresis width and the drift rate of an ISFET with a-C:H as a detection membrane according to the present invention. An ISFET 81 with a-C:H as a detection membrane (called a-C:H ISFET) is immersed in a buffer solution 82 such as a standard buffer solution in a container (not labeled). A drain/source (not shown) of the a-C:H ISFET 81 is connected to a constant voltage/current circuit 83 (such as a negative feedback circuit) through two wires 811 and 812. The drain-source voltage and the drain-source current of the a-C:H ISFET 81 are fixed by the constant voltage/current circuit 83. 10 15

A reference electrode 84 is disposed in the buffer solution 82, wherein one end of the reference electrode 84 is connected to the constant voltage/current circuit 83 through a wire 841. A heater 85 disposed outside the container is connected to a PID (Proportional-Integral-Derivative) temperature controller 86. Both the heater 20 25 85 and the PID temperature controller 86 keep the buffer solution 82 at a constant temperature (preferably 25°C) detected by a thermocouple 87 connected to the PID temperature controller 86. The above buffer solution 82, every device connected thereto, and the heater 86 are

disposed in a light-isolating container 88 to reduce the effect of light on the measuring results.

The constant voltage/current circuit 83 is connected to a current/voltage measuring device 89 composed of two digital multimeters detecting whether the source-drain current and the source-drain voltage of the a-C:H ISFET 81 move towards stability. Also, the constant voltage/current circuit 83 is connected to a voltage-time recorder 810 for setting and recording the output voltages during each recording period.

Fig. 9 shows a schematic diagram of the constant voltage/current circuit 83 according to the present invention. The constant voltage/current circuit 83 is connected to the source/drain of the a-C:H ISFET 81 through the wires 811 and 812, and is connected to the reference electrode 84 through the wire 841. The source-drain voltage is fixed at a constant value (preferably 0.2V) by adjusting the variable resistance R1. The source-drain current is fixed at a constant value (preferably 80 μ A). In this case of the negative feedback circuit, the output voltage and the gate voltage are reduced and finally the drain-source current I_{DS} is reduced when the increasing drain-source current I_{DS} increases the source voltage. The circuit 83 has advantages of simplicity, low cost, ease of operation and no need for adjustment of the measuring point.

Next, returning to Fig. 4, a schematic cross-section of the a-C:H ISFET according to the present invention, the a-C:H ISFET is formed on a semiconductor substrate 20 such as a p-type silicon substrate. In this case, a pair

of source/drain regions 21 separated from each other are formed approaching the top surface of the semiconductor substrate 20, and are connected to constant voltage/current circuit by an aluminum contact plug 22 and an aluminum wire 23. On the semiconductor substrate 20 between the two drain/source regions 21, a gate oxide 24, such as a silicon oxide layer, and an a-C:H detection membrane 25 are formed sequentially. An epoxy resin 26 seals the device but exposes the a-C:H detection membrane 25. As well, a metal-aluminum layer 27 is formed at the bottom of the semiconductor substrate 20 to decrease the channel-adjusting effect.

Hereinafter, a method to measure the hysteresis width and the drift rate of the a-C:H ISFET in detail is described with reference to Figs. 2, 8 and 9.

With reference to the method of measuring the hysteresis width of the a-C:H ISFET, first, the drain-source current and the drain-source voltage of the a-C:H ISFET 81 are fixed by the constant voltage/current circuit (negative feedback circuit) 83. In this step, the a-C:H ISFET 81 and the reference electrode 84 are connected to the constant voltage/current circuit 83, and are immersed in the solution. Next, the drain voltage V_D of the a-C:H ISFET 81 is set at 0.2V by adjusting the variable resistant R1 and measurement by one digital multimeter. Also, the drain-source current I_{DS} is set at 80 μ A by adjusting the variable resistant R2 and measurement by the other digital multimeter. The a-C:H ISFET 81 is then placed in a standard solution to maintain stability.

After, the a-C:H ISFET 81 is immersed in a buffer solution. Next, the voltage-time recorder records the gate-source output voltages of a-C:H ISFET 81. The hysteresis width of the a-C:H ISFET 81 in accordance with the pH of the buffer solution is then measured. In the present invention, hysteresis width is measured in pH=6→2→6→10→6 order, namely pH=6-5-4-3-2-3-4-5-6-7-8-9-10-9-8-7-6, wherein each measuring result is achieved at the time the pH is changed for one minute, the loop time is 1020 seconds, and each time the pH changes by one unit. Particularly, choosing the pH=6-2-6-10-6 order measures hysteresis within the pH range between 1 and 9. Also, the hysteresis within the pH range between 1 and 9 are measured in the same way, wherein each result is at the time when the pH is changed for two minutes and four minutes, the loop time is 2040 seconds and 4080 seconds. Table 2 shows the hysteresis width of the a-C:H ISFET in pH=6→2→6→10→6 order at different loop time. By the same method, all of the hysteresis widths at different pH values can be measured, which is helpful in performing the reverse compensation method.

Table 2 the hysteresis width of the a-C:H ISFET in pH=6→2→6→10→6 order at different loop time

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Loop time(seconds)	Hysteresis width(mV)
1020	2.38
2040	3.86
4080	4.5
8160	5.4
16320	7.22

The relationship between the hysteresis width, the pH and time measured in pH=6→2→6→10→6 order are shown in Fig. 10. As shown in Figs. 10, the hysteresis width of the a-C:H ISFET increases as the loop time increases.

5 Next, with reference to the drift rate, the drain-source current and the drain-source voltage of the a-C:H ISFET are fixed by the constant voltage/current circuit (negative feedback circuit) 83. The a-C:H ISFET 81 and the reference electrode 84 are then connected to the 10 constant voltage/current circuit 83, and immersed in the solution. Next, the drain-source current I_{DS} of the ISFET 81 is set by adjusting the variable resistor R2 and measurement by one digital multimeter. Also, the drain-source voltage V_{DS} is set at 0.2V by adjusting the 15 variable resistor R1 and measurement with the other digital multimeter. Afterwards, the a-C:H ISFET is immersed in the buffer solution for a period of time. Finally, the gate-source output voltage is recorded by the voltage-time recorder, thereby obtaining the drift 20 rate of the ISFET.

It should be noted that current generated by illumination affects the drift rate. Hence, the drain-source current should be adjusted between 10 μ A and more than one hundred μ A to reduce the illumination effect. 25 As well, stability is easily affected by temperature when the drain-source current I_{DS} is extremely large. Accordingly, the drain-source current is preferably set at 10~300 μ A.

Table 3 shows the drift rates of the a-C:H ISFET at 30 pH 1~10, and Fig. 11 shows the relationship between the

drift rate and the pH. The drift rate of the a-C:H ISFET is obtained from the slope of a curve whose time parameter is more than the fifth hour.

Table 3 the drift rates of the a-C:H ISFET at pH 1-10

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pH	Drift rate (mV/h)
1	0.44
2	0.5
3	0.55
4	0.68
5	1.06
6	1.3
7	1.56
8	1.8
9	2.12
10	2.38

10 It is believed that the drift behavior is more obvious when the pH is large. Also, when the data approximately forms a line, the drift rates at any other pH can be estimated. This is useful when performing reverse compensation.

15 The method of forming the a-C:H ISFET according to the present invention is simple, has a low cost and novel technology. The measuring methods and apparatus can accurately measure hysteresis width and drift rate of the a-C:H ISFET, and also hysteresis width and the drift rate of the ISFETs with other types of detection membranes.

20 While the invention has been described by way of example and in terms of the preferred embodiments, it is to be understood that the invention is not limited to the disclosed embodiments. To the contrary, it is intended to cover various modifications and similar arrangements

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(as would be apparent to those skilled in the art). Therefore, the scope of the appended claims should be accorded the broadest interpretation to encompass all such modifications and similar arrangements.